

Docket No.: 49959-220

#12/IDS
9-29-03
PATENT *Haug*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

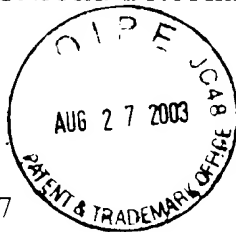
In re Application of

Gilad ALMOGY, et al.

Serial No.: 09/986,137

Filed: November 07, 2001

For: SPOT GRID ARRAY ELECTRON IMAGING SYSTEM



: Customer Number: 20277
: Confirmation Number: 4655
: Group Art Unit: 3662
: Examiner: To be assigned

INFORMATION DISCLOSURE STATEMENT

Mail Stop DD
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached form PTO-1449. It is respectfully requested that the references be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Each English language reference was cited in a corresponding foreign application search report or office action and its citation is hereby

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Respectfully submitted,

MCDERMOTT, WILL & EMERY

A handwritten signature in cursive script that reads "Michael A. Messina".

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INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(PTO-1449)


 ATTY. DOCKET NO.
49959-220

 SERIAL NO.
09/986,137

 APPLICANT
Gilad ALMOGY, et al.

 FILING DATE
November 07, 2001

 GROUP
3662

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO	Document Number Number-Kind Code, etc.	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear
		US 6,040,909	03/21/00	Hasegawa et al	
		US 6,248,988	06/19/01	Krantz	
		US 6,130,428	10/10/00	Pasch	
		US 5,937,966	08/03/96	Schneider et al	
		US 3,894,332	07/15/75	Nathanson et al	
		US US 2003/0042434 A1	03/06/03	Mankos et al	
		US 5,659,420	08/19/97	Wakai et al	
		US			

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO	Foreign Patent Document Country Codes, Number & Kind Code(s) ("A1", "B1", etc.)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation	
						Yes	No
		GB 2339960 A	02/09/00	United Kingdom			
		WO 01/84585 A1	11/08/01	PCT			
		WO 02/23172 A2	03/21/02	PCT			
		EP 0948027 A2	10/06/99	Europe			
		WO 01/09920 A1	02/08/01	PCT			
		WO 02/15223 A1	02/21/02	PCT			
		WO 02/23580 A1	03/21/02	PCT			

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER'S INITIALS	CITE NO	Include name of the author (in CAPITAL LETTERS); title of the article (when appropriate); title of the item (book, magazine, journal, serial, symposium, catalog, etc.); date; page(s); volume/issue number(s); publisher, city and/or country where published
		International Search Report dated August 4, 2003
		"High throughput electron lithography with the multiple aperture pixel by pixel enhancement of resolution concept", Krutz, P., J. Vac. Sci. Technol. B 16(6), Nov/Dec 1998
		"Microlens arrays with spatial variation of the optical functions", Hessler, Th., et al., Pure Appl. Opt. 6:1937-1973-681
		"A Microlens Direct-Write Concept for Lithography", Davidson, M., SPIE 3048, p. 346-355
		"Immersion lithography at 157 nm", Switkes, M., et al., J. Vac. Sci. Technol. B, Vol. 19, No. 6, Nov/Dec 2001, pp. 2359-2369
		"Liquid immersion deep-ultraviolet interferometric lithography", Hofnagle, J., et al., J. Vac. Sci. Technol. B 17(6), Nov/Dec 1999, pp. 3306-3309
		"An Overview of the Performance Envelope of Digital Micromirror Device (DMD) Based Projection Display Systems", Sampell, J. B., Society for Information Display 1994 International Symposium (San Jose, Jun. 12-17, 1994), pp. 1-4
		"UV Thermoresists: Sub 100nm Imaging Without Proximity Effects", Gelbart, D., et al., SPIE Vol. 3676, pp. 786-793

EXAMINER

DATE CONSIDERED